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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/707,824	01/15/2004	Long-Hui Lin	LKSP0029USA	1823
27765	7590 05/13/2005		EXAMINER	
NORTH AMERICA INTERNATIONAL PATENT OFFICE (NAIPC) P.O. BOX 506			COLEMAN, WILLIAM D	
	MERRIFIELD, VA 22116		ART UNIT	PAPER NUMBER
			2823	
			DATE MAILED: 05/13/2005	

Please find below and/or attached an Office communication concerning this application or proceeding.

4 · •		
	Application No.	Applicant(s)
Office And O	10/707,824	LIN, LONG-HUI
Office Action Summary	Examiner	Art Unit
	W. David Coleman	2823
The MAILING DATE of this communication a Period for Reply	ppears on the cover sheet with the	correspondence address
A SHORTENED STATUTORY PERIOD FOR REF THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a r - If NO period for reply is specified above, the maximum statutory perion - Failure to reply within the set or extended period for reply will, by stat Any reply received by the Office later than three months after the mail earned patent term adjustment. See 37 CFR 1.704(b).	N. 1.136(a). In no event, however, may a reply be teleply within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from the cause the application to become ABANDON	timely filed ays will be considered timely. m the mailing date of this communication. IED (35 U.S.C. § 133).
Status		
1) Responsive to communication(s) filed on 15	January 2004	·
2a) ☐ This action is FINAL . 2b) ☑ The section is FINAL .	his action is non-final.	•
3) Since this application is in condition for allow closed in accordance with the practice unde	·	
Disposition of Claims		
4) ⊠ Claim(s) <u>1-9</u> is/are pending in the application 4a) Of the above claim(s) is/are withd 5) □ Claim(s) is/are allowed. 6) ⊠ Claim(s) <u>1-9</u> is/are rejected. 7) □ Claim(s) is/are objected to. 8) □ Claim(s) are subject to restriction and	rawn from consideration.	
Application Papers		
9) The specification is objected to by the Exami	ner.	•
10) The drawing(s) filed on is/are: a) a	ccepted or b) objected to by the	Examiner.
Applicant may not request that any objection to the	- · ·	• •
Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the	, , , , , , , , , , , , , , , , , , , ,	•
Priority under 35 U.S.C. § 119	,	
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority docume 2. Certified copies of the priority docume 3. Copies of the certified copies of the priority docume application from the International Bure * See the attached detailed Office action for a life.	ents have been received. ents have been received in Applica rionty documents have been receive eau (PCT Rule 17.2(a)).	ation No ved in this National Stage
Attachment(s)		
1) Notice of References Cited (PTO-892)	4) Interview Summa	ry (PTO-413)
Notice of Draftsperson's Patent Drawing Review (PTO-948) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/C Paper No(s)/Mail Date	Paper No(s)/Mail 5) Notice of Informal 6) Other:	Date Patent Application (PTO-152)

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DETAILED ACTION

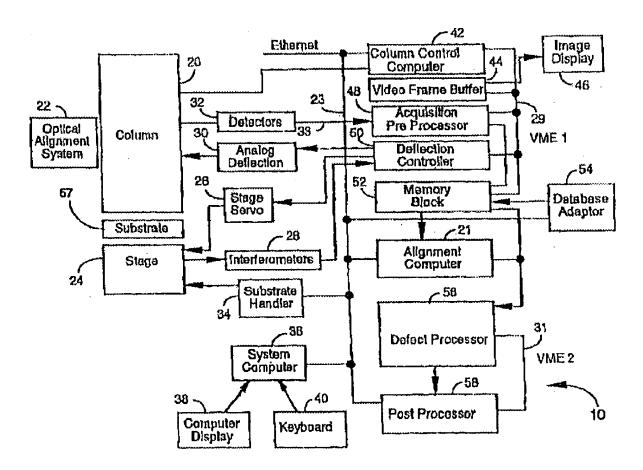
Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 1-9 are rejected under 35 U.S.C. 102(b) as being anticipated by Satya et al., U.S. Patent 6,445,199 B1.

Satya discloses a semiconductor process as claimed. See FIGS. 1-35, where Satya teaches the following limitations.



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3. Pertaining to claim 1, <u>Satya</u> teaches a method of defect review comprising following

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steps:

providing a wafer with a plurality of defects;

performing a defect inspection to detect the defects; performing an automatic defect

classification according to a database to separate the defects into a plurality of defect types; and

performing a defect review;

wherein each defect type has different sampling ratios in the defect review according to its

influence degree of process yield (see column 7, lines 14-48).

4. Pertaining to claim 2, <u>Satya</u> teaches the method of claim 1 wherein the database

comprises information about the plurality of defect types and defect information corresponding

to each defect type (see FIG. 3).

5. Pertaining to claim 3, Satya teaches the method of claim 2 wherein the defect information

comprises the influence degree of the process yield of each defect type.

6. Pertaining to claim 4, Satva teaches the method of claim 3 wherein the database separates

the defect types into killer defects and non-killer defects according to the influence degree of the

process yield (column 31, lines 3-14).

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7. Pertaining to claim 5, <u>Satya</u> teaches the method of claim 4 wherein the sampling ratio of the killer defects in the defect review is larger than that of the non-killer defects (column 31, lines 25-51).

- 8. Pertaining to claim 6, <u>Satya</u> teaches the method of claim 3 wherein the database separates the defects into pre-layer defects and adding defects, and further separates the adding defects into killer defects and non-killer defects (see column 31).
- 9. Pertaining to claim 7, <u>Satya</u> teaches the method of claim 6 wherein the defect review focuses on the adding defects.
- 10. Pertaining to claim 8. <u>Satya</u> teaches the method of claim 1 wherein after finishing the defect inspection, a judgment of cluster defects is performed and a defect review with a high sampling ratio is performed on the cluster defects if the cluster defects exist.
- 11. Pertaining to claim 9, <u>Satya</u> teaches the method of claim 1 wherein the database is updated according to the result of the defect review after finishing the defect review.

Conclusion

12. Any inquiry concerning this communication or earlier communications from the examiner should be directed to W. David Coleman whose telephone number is 571-272-1856.

The examiner can normally be reached on Monday-Friday 9:00 AM - 5:30 PM.

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- 13. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on 571-272-1855. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.
- 14. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

to

W. David Coleman Primary Examiner Art Unit 2823

WDC